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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10088098	FILING DATE 05/30/2002	CLASS 219	SUBCLASS 444.100	GAU 3742	EXAMINER Pat Fagua
**APPLICANTS: Ito Yasutaka; Hiramatsu Yasuji;					
BEST AVAILABLE COPY					
**CONTINUING DATA VERIFIED: THIS APPLICATION IS A 371 OF PCT/JP01/06395 07/25/2001 JLF					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2000-223767 07/25/2000 JLF					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input checked="" type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO			
35 USC 119 conditions met <input checked="" type="checkbox"/> yes <input type="checkbox"/> no		221158US2PCT			
Verified and Acknowledged Examiners's initials JLF					
TITLE : Ceramic substrate for semiconductor manufacture/inspection apparatus, ceramic heater, electrostatic clampless holder, and substrate for wafer prober					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Assistant Examiner	
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.
		Print Fig:	
		Application Examiner	
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	
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